

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:
Chih-Chien Liu, et al.
Serial No: 09/546,174
Confirmation No.: 4793
Filed: April 11, 2000

For: High Density Plasma Chemical Vapor
Deposition Process

Art Unit: 1711
Examiner: Sergent, Rabon A.

PETITION FOR EXTENSION OF TIME

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

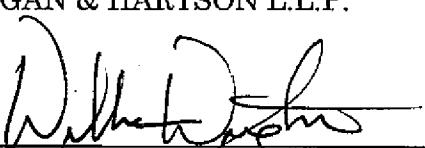
In accordance with 37 C.F.R. 1.136, Applicant respectfully petitions the Commissioner for a three-month extension of time extending to December 20, 2007, the period for response to the Office Action dated June 20, 2007. Please charge Deposit Account No. 50-1314 the Extension fee in the amount of \$1,050.00. The responsive papers are attached.

Please charge any insufficiency or credit any overpayment to Deposit Account No. 50-1314. A copy of this petition is enclosed.

Respectfully submitted,

HOGAN & HARTSON L.L.P.

Dated: December 20, 2007

By: 
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